

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

APPLICANT: M. Hatanaka et al. CONF. NO.: 8004  
U.S. SERIAL NO.: 09/471,829 EXAMINER: P. Connolly  
FILED: December 23, 1999 GROUP: 2877  
FOR: APPARATUS AND METHOD FOR MEASURING THE THICKNESS  
OF A THIN FILM VIA THE INTENSITY OF REFLECTED LIGHT

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

**AMENDMENT**

Applicants are in receipt of the Office Action dated April 23, 2007 of the above-referenced application. Please amend the application as follows:

**Amendments to the claims** are reflected in the listing of claims which begins on page 2 of this paper.

**Remarks** begin on page 7 of this paper.

OK TO ENTER  
PJC  
07.07.2007